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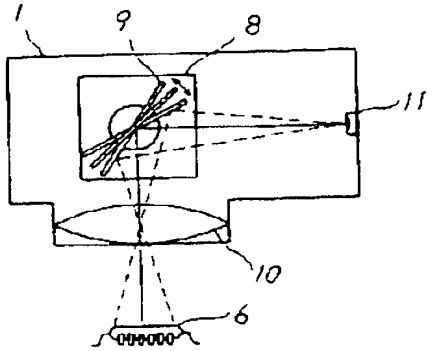
TITLE : METHOD AND APPARATUS FOR INPUTTING IMAGE OF LARGE VISUAL FIELD



ABSTRACT : PURPOSE: To obtain an image of arbitrary dimensions and to shorten an image input time by conducting image sensing in the direction of the X axis by a linear sensor and by conducting scanning in the direction of the Y axis by varying the angle of a mirror programmably.

CONSTITUTION: A galvanocamera 1 uses a linear sensor 11 of 2048×1 so as to obtain visual field sizes of 51.2×51.2mm^2 and a resolution of 25μm. The angle of a galvanomirror 9 put on the optical axis of this sensor is varied by a galvanomotor 8, scanning in the direction of the Y axis of a semiconductor device 6 is executed and an image is sensed by the sensor 11. Since the operation of the mirror 9 is programmable, the scanning is executed as needed, being matched with package sizes of the semiconductor 6 which is an object of inspection. In the case when the mirror 9 is operated at an equal angular speed on the occasion of the scanning, the amount of movement becomes large as the angle becomes large, and therefore distortion occurs in an image. To cope with this, correction is applied to set the amount of movement at equal intervals. An image processing is conducted by using the image obtained by a series of operations, and thereby inspection of the external appearance of the semiconductor 6 is executed.